# VALQUA Semiconductor Industry Products

# HYREC ARMOR ™

High Performance Elastomer FKM O-Ring

#### Product & Benefits

HYREC ARMOR ® is a softer FKM suited for static seal locations, with excellent purity and improved radical resistance compared to the conventional FKM. It may be used for dry etch, ashing, CVD processes.



#### Featured Benefits

- A Softer FKM with Excellent Compression Set for Static Locations
- Low Adhesion to Quartz and Improved Radical Resistance

### **Applications**

- Dry Etch Equipment
- Plasma Enhanced CVD Equipment
- Plasma Ashing Equipment

### Typical Properties

Color	Transparent Deep Amber
Hardness (Chara A)	·
Hardness (Shore A)	58
Tensile Strength (MPa)	13
Elongation (%)	440
Modulus 100% Elongation (MPa)	1.2
Maximum Temperature (°C)	200
Compression Set (%)	38

Compression Set: 25% compression at 200℃ for 72 hours Values above are actual measurements, not standards

#### Contact Us

Valqua America, Inc. 4655 Old Ironsides Dr #380 Santa Clara, CA 95054 www.valqua-america.com

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Valgua America, Inc.

+1-408-986-1425

Email: info@valqua-america.com

# Additional information

## **HYREC ARMOR** ™

VALQUA AMERICA, ING

#### Mechanical Properties

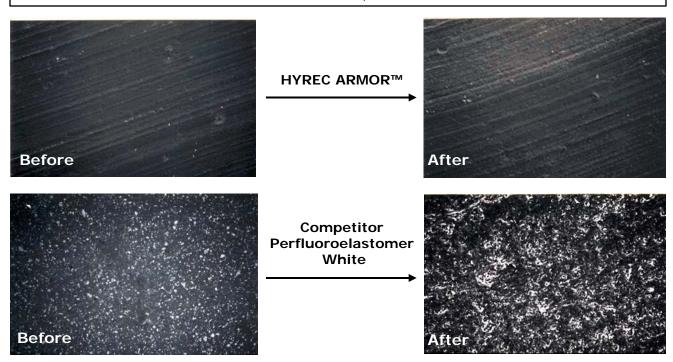
#### Actual Equipment Evaluation Example

Scanning electron micrograph of elastomer surface after plasma exposure

**Equipment:** Etcher

**O-ring Size**: AS568A-207 **Gas**: Cl<sub>2</sub> +BCl<sub>3</sub>+Ar **Plasma Power**: 1000-1500W **Temp**: 100-200°C

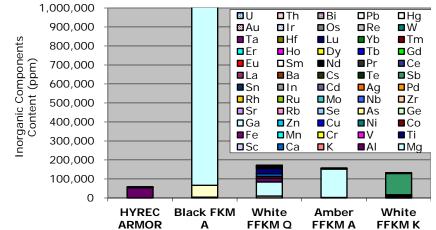
**Evaluation Period**: HYREC ARMOR 2 months Competitor 1.5 months



### Inorganic Components Content

**Test Conditions** 

Measuring method: ICP/MS analysis Inorganic elements: Total of 62 elements





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Tel: +1-408-986-1425

Email: info@valqua-america.com